

12英寸自动减薄设备

12 INCH AUTOMATIC GRINDER

AG7500

● 最大有效加工尺寸 (mm)

Maximum effective product size (mm)

Max.Ø300 (Ø4" ~ Ø12")

● 主轴配置方式

Configuration method of spindle

单主轴

Single-spindle



• 特点 FEATURE

采用直观便捷的整机操作界面，可选择不同尺寸不同规格的加工配置文件。

With the intuitive and convenient operation interface of the whole machine, you can select processing configuration files of different sizes and specifications.

采用精密进口滚珠丝杆、直线导轨，高精度电机，进行 Z 向精密控制；最小分辨率在 0.1UM/S。

Precision imported ball screw, linear guide rail and high-precision motor are used for Z-direction precision control; The minimum resolution is 0.1um/s.

可有效于硬质和脆性材料以及电子元件产品的研削加工。

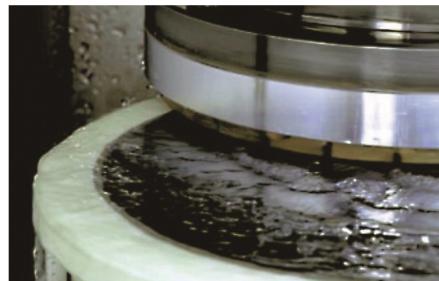
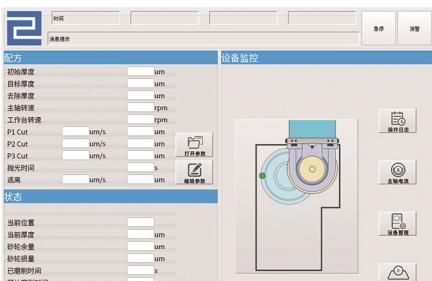
In-Feed spindle feed type High precision grinding.

采用高刚性气浮主轴，高可靠性与运动精度的承片组件，加之高精度测厚仪；保证加工全程的稳定、可靠。

Adopt high rigid air bearing spindle, high reliability and motion precision bearing plate assembly, and high precision thickness gauge; Ensure the stability and reliability of the whole process.

单主轴，单工作台，结构紧凑的减薄机，最大可对应 12 英寸的加工物。

Single-spindle, single-worktable, compact thinning machine, which can correspond to a maximum of 12 inches of workpiece.



• 功能 FUNCTION

注:「*」为选配功能,支持个性化定制
PS:「*」is an optional feature that can be customized by the customer

操作日志记录

Operation log record

抽雾过滤系统

Mist extraction and filtration system

主轴水冷系统

Spindle water cooling system

功能模块化&软件定制

Functional modularity & software customization

12英寸晶圆等材料磨削

Grinding of 12-inch wafer and other materials

实时高精度接触式晶圆测厚

Real-time, high-precision contact wafer thickness measurement

真空预警与真空管路去水

Vacuum warning and vacuum line de-watering

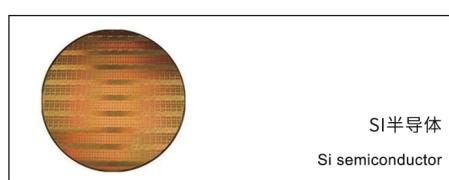
• 参数 PARAMETER

	参数	描述	参数	描述
主轴	Spindle		高频电机内嵌空气静压主轴	High-frequency motor built-in aerostatic spindle
额定输出功率 (kW)	Rated output power (kW)	7.5		
Z轴 Z axis	转速 (Rpm)	Rotary speed (Rpm)	0-4000	
	行程 (mm)	Stroke (mm)	80	
	进刀速度 (μm)	Feed speed (μm)	0.0001-0.08	
	快退速度 (μm)	Fast rewind speed (μm)	50	
高度计 Altimeter	最小位移量 (μm)	Minimum displacement (μm)	0.1	
	分辨率 (μm)	Resolution (μm)	0.1	
	测量范围 (μm)	Measuring range (μm)	0-1250	
	分辨率 (μm)	Resolution (μm)	0.1	
吸盘 Sucker	重复精度 (μm)	Repetition precision (μm)	±0.5	
	工作台型式	Workbench type	多孔陶瓷式工作台	Porous ceramic worktable
	转速 (Rpm)	Rotary speed (Rpm)	0-500	
磨轮 Mill wheel	工作台清洗	Workbench cleaning	油石手动清洗	Manual cleaning of oilstone
	金刚石砂轮 (mm)	Diamond grinding wheel (mm)	Ø300	
真空发生器 Vacuum generator	排风速度	Exhaust speed	>5m³/min	
	真空压力 (kPa)	Vacuum pressure (kPa)	-90(水温 15°C, 流量 1L/min 时) -90 (at water temperature of 15 °C and flow of 1L/min)	
	电动机功率 (kW)	Motor power (kW)	2.4	
	用水量 (L/min)	Water consumption (L/min)	3(水温>22°C), 1(水温<22°C) 3 (water temperature>22 ° C), 1 (water temperature<22 ° C)	
加工精度 Machining accuracy	单片晶圆内厚度差 (μm)	Thickness difference in single wafer (μm)	±3	
	不同间晶圆厚度差 (μm)	Thickness difference between different wafers (μm)	±3	
设备重量 (kg) 设备尺寸/W*D*H (mm)	精加工面粗糙度	Finish surface roughness	Ry 0.13(2000#) Ry 0.15(1400#)	
	Weight (kg)	Weight (kg)	≈2,100	
	Size / W*D*H (mm)	Size / W*D*H (mm)	840*1,920*1,750	

• 应用 APPLICATION



半导体晶圆



Si半导体



陶瓷